



In Prague 12th September 2012

Evaluation of the IUVSTA Technical Training Course Grant in 2012 provided to the Czech Vacuum Society

Course location: Pyramida – Panský dům hotel, Jizerské hory mountains, Jizerka 20, 46850 Polubný, Czech Republic

Date of the Course: 21-24 May, 2012

Title: **Advanced Deposition Techniques**

The course was a continuation of the courses organized by Czech Vacuum Society every year.

It consisted of 8 lectures:

1. Introduction to physical deposition techniques, P. Sobotík, Faculty of Mathematics and Physics, Charles University in Prague
2. Application of FIB for fabrication of functional nanostructures, O. Tomanec, Faculty of Mechanical Engineering, Brno University of Technology
3. Selective Growth of Nanostructures, T. Šikola, Faculty of Mechanical Engineering, Brno University of Technology
4. Fabrication and monitoring of coordinated meshes using organic ligands and metallic atoms under UHV conditions, J. Čechal, Faculty of Mechanical Engineering, Brno University of Technology
5. Advanced deposition techniques by magnetron sputtering, J. Vyskočil, HVM Plasma, Prague
6. Application of plasma processes in micro and nanotechnologies, L. Zajíčková, Faculty of Science, Masaryk University in Brno
7. Pulsed laser deposition – PLD, J. Lančok, Institute of Physics, Academy of Science of the Czech Republic, Prague
8. Molecular Beam Epitaxy (MBE), K. Olejník, Institute of Physics, Academy of Science of the Czech Republic, Prague

Each lecturer elaborated short version of the lecture (text, colored figures, 4 pages minimum) published in CVS bulletin “Zpravodaj”. A copy of the bulletin was provided to each participant at the registration.

The Technical Training Course (TTC) was attended by 51 persons – students, young researchers and technicians from the whole country working in the field of vacuum deposition techniques and related branches. IUVSTA support helped us to cover mainly stay costs of the teachers and print expenses of the bulletin. It permitted to lower the TTC fee for all participants. In addition, selected participants (students and CVS members) were partially supported by deduction of the stay expenses (approximately 50 EUR per person). For details see the table below.

Total TTC costs	7000 EUR
IUVSTA support	2500 EUR
Number of participants	51
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Stay expenses of the teachers (8 persons)	900 EUR
Conference hall and technical equipment	100 EUR
CVS bulletin print costs	500 EUR
Supported participants (20 persons)	1000 EUR
Total expenses covered by IUVSTA grant	2500 EUR

A part of TTC was “Company Evening” – 3 hours of presentations and discussions with representatives of vacuum production (and related products) from Czech as well as international companies. All costs of this evening and stay expenses of the representatives were completely covered from company fee.

During three days the TTC was attended by 62 participants and representatives. The lectures had very high level and fulfilled the expectations of the participants and organizers. The TTC “Advanced Deposition Techniques” was successful from the point of view of its scientific as well as social level. The organizers thank to IUVSTA for the support.

On behalf of the TTC organizers

Karel Mašek
President of the Czech Vacuum Society